# Fractal Analysis of Surface Topography of Solid Oxide Fuel Cell Materials

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Abstract. In this work, we investigate the hierarchical surface topography of solid oxide fuel cell electrolytes consisting of zirconia stabilized with 10% Sc<sub>2</sub>O<sub>3</sub> and 1% CeO<sub>2</sub> (1Ce10ScSZ) synthesized at 1300-1400 °C and anodes of 60 wt% 1Ce10ScSZ and 40 wt% NiO synthesized at 1250 to 1550 °C. The fractal dimension of AFM images of the films was determined by the cube counting method, the triangulation method and by means of the PSD slope at large wavenumbers. RMS roughness and correlation lengths were derived from the fit to the model PSD.

**Key words:** Atomic force microscopy, solid oxide fuel cell materials, fractal analysis, power spectrum density.

#### I. INTRODUCTION

By taking advantage of the scaling property of many physical systems reducing the amount of data required for structural characterization [1], hierarchical structures might be adequately characterized by atomic force microscopy (AFM) with resolution from about 10 nm to the micrometer range. The investigation of surface topography of porous materials by means of atomic force microscopy (providing already digitized images which are ready for computer analysis) provides thus a tool for the prediction of surfacesensitive properties such as the catalytic reactivity. Characteristic parameters like surface roughness, local fractal dimension, grain size and superstructures in the morphology are most preferably estimated by the Fourier power spectral density (PSD) [2].

In this work, we evaluate the hierarchical surface topography of solid oxide fuel cell electrolytes consisting of zirconia stabilized with 10% Sc<sub>2</sub>O<sub>3</sub> and 1% CeO<sub>2</sub> (1Ce10ScSZ) synthesized at 1300-1400°C and anodes of 60 wt% 1Ce10ScSZ and 40 wt% NiO synthesized at 1250 to 1550 °C.

### **II.** THEORY

Surface topography is usually described in terms of surface roughness. Surface roughness is solely a function of height, that is, information about lateral topography is lost.

Power spectral density (PSD) is a technique that calculates power (roughness amplitude squared) as a function of spatial wavelengths k of the features that are contributing to the surface image. It is suitable for surfaces that this can be well approximated by a series of sine waves. Thin film surfaces are known to be self-affine, e.g., they are well modelled using anisotropic fractals and their topography is well described using the k-correlation model (also called ABC model) yielding in the one-dimensional case (assuming perfectly isotropic surfaces) [3]

$$PSD = \frac{A}{(1+B^2k^2)^{C/2}}.$$
 (1)

The PSD identifies wavelengths of features that contribute to the surface structure. It describes how the power of the Fourier transform of the surface height is distributed with wavenumber of the spatial frequency k in reciprocal space. The parameter A describes the low-frequency limit of the spectrum. The parameter B sets the point of the transition between the smooth low-frequency and fractal highfrequency behaviour of the PSD. It defines a correlation length beyond which the surface height fluctuations are not correlated thus representing a mean grain size. The parameter C allows analysing the growth mechanism [1]. The integration of the one-dimensional PSD yields the RMS roughness  $\sigma$  of the surface

$$\sigma_{1-D}^{2} = \int_{f_{\min}}^{J_{\max}} PSD_{1-D}(k) \cdot dk$$
 (2)

## **III. EXPERIMENTAL**

Microstructure of the SOFC materials was investigated by AFM using an NTEGRA Therma scanning probe microscope (NT-MDT, Zelenograd, Russia). Tapping mode imaging was performed in air using silicon cantilevers (Type NSG01, NDT-MDT, Zelenograd, Russia). The twodimensional AFM image was averaged over the profiles traced in fast scan direction using the Open Source Software Gwyddion 2.21 using Daniell (equal weight) window [4]. This allows reducing noise due to instrument drift appearing more pronounced in the slow scan direction. Moreover, the averaging over 256 scans is approximately equivalent to the integration of the two-dimensional PSD over the slow scan direction [5]. In order to increase data reliability, PSDs were recorded using scans of  $20x20 \ \mu m^2$  and  $40x40\mu m^2$ . The resulting PSD was calculated as the geometrical average over all PSDs [6].

The fractal dimension of AFM images of the films was determined by the cube counting method, the triangulation method and by means of the PSD slope at large wavenumbers [7]. RMS roughness, correlation lengths and local fractal dimension were derived from the fit to the model PSD.

### IV. RESULTS AND DISCUSSION

Fig. 1 illustrates the PSDs of the 60 wt% 1Ce10ScSZ -

International Conference on Oxide Materials for Electronic Engineering OMEE-2012

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40 wt% NiO samples in dependence on annealing temperature. According to eq. (1), the PSD will run (with some fluctuations) at small wavenumbers parallel to the k axis. However, some of the PSD curves display a maximum in this region. This feature should be attributed to the fact that the low-frequency PSD components are not very reproducible because not enough data points are available in the averaging procedure to obtain adequate statistics [8]. This maximum is less pronounced when data of different scan lengths is geometrically averaged as proposed in [6].

The related fractal dimensions and PSD parameters are compiled in tables 1 and 2.



Fig. 1. Power spectral density of the surface profile calculated from AFM images of 60wt% 1Ce10ScSZ – 40 wt% NiO samples in dependence on annealing temperature. The fit to the ABC model is shown by solid lines.

Table 1. k-correlation approximation (ABC-model) of 60 wt% 1Ce10ScSZ-40 wt% NiO samples in dependence on annealing temperature.

Annealing temperature, °C	$A$ , $\mu$ m <sup>4</sup>	<i>B</i> , μm	С
1300	1.30	6.4	3.25
1350	0.28	4.0	4.7
1400	0.05	2.0	6.0

Table 2. Fractal dimensions and RMS roughness of 60wt% 1Ce10ScSZ-40wt% NiO samples in dependence on annealing temperature.

Annealing temperature, °C	Cube counting	Triangu- lation	PSD	RMS rough- ness, μm
1300	2.16	2.18	2.375	0.392
1350	2.16	2.22	(1.65)	0.180
1400	2.18	2.28	(1.0)	0.267

With regard to the finite numbers of pixels of an AFM image, the triangulation method provides a more reliable value of fractal dimension while cube counting underestimates the real value [7]. PSD does not allow deriving a reliable fractal dimension without applying before calculation of the PSD a more appropriate window function for the FFT algorithm in order to reduce finite pixel number effects and to minimize the arising from finite pixel numbers spectral leakage [9].

The fractal dimensions and ABC model parameters of the 1Ce10ScSZ samples are summarized in tables 3 and 4.

Table 3. k-correlation approximation (ABC-model) of 1Ce10ScSZ samples in dependence on annealing temperature.

Annealing temperature, °C	$A$ , $\mu$ m <sup>3</sup>	<i>B</i> , μm	С
1250	0.17	6.4	3.6
1300	0.80	7.2	3.5
1400	0.04	2.5	6
1450	0.11	4.8	3.6
1550	0.25	5.6	3.6

Table 4. Fractal dimensions and RMS roughness of 1Ce10ScSZ samples in dependence on annealing temperature.

Annealing temperature, °C	Cube counting	Triangu- lation	PSD	RMS rough- ness, μm
1250	2.23	2.3	2.20	0.318
1300	2.18	2.22	2.25	0.738
1400	2.23	2.32	(1.0)	0.253
1450	2.25	2.32	2.2	0.084
1550	2.2	2.25	2.2	0.433

## V. CONCLUSIONS

In this work we have demonstrated that the local fractal dimension determined from AFM images is an appropriate and easy to use tool for the characterization of hierarchical surfaces of solid oxide fuel cell materials. With regard to the finite numbers of pixels of an AFM image, the triangulation method provides more reliable values of fractal dimension while the PSD allows analysis of structure evolution.

#### ACKNOWLEDGMENT

This work was supported by the International Bureau of the German Federal Ministry of Education and Research by contract 01DK12017 and by the Erasmus Mundus ECW Programme of the European Union (A.P.).

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